

Form PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)	ATTY DOCKET NO. 104-248P	APPLICATION NO. New
APPLICANT Anders THUREN		
FILING DATE August 27, 1999		GROUP

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
JP	5 5 3 3 1 7 0	7/2/1996	Teitzel et al.			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION
						YES NO
JP	0 4 6 7 0 7 6	1/22/1992	E P O			

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER <i>Joseph R. Rhyne</i>	DATE CONSIDERED <i>9/15/03</i>
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-1449

**INFORMATION DISCLOSURE CITATION
IN AN APPLICATION**

(Use several sheets if necessary)

 ATTY DOCKET NO.
0104-0248P

 APPLICATION NO.
09/380,270

 APPLICANT
Anders THUREN

 FILING DATE
August 27, 1999

 GROUP
2622

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	Kind	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	US						
	US						
	US						
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FOREIGN PATENT DOCUMENTS

	Office	DOCUMENT NUMBER	Kind	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION	
								YES	NO

OTHER DOCUMENTS

(Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.

JP	PROCEEDINGS OF SPIE Vol. 3997 (2000), Emerging Lithographic Technologies IV, "Lossless Layout Compression for Maskless Lithography Systems," Vito DAI et al.
JP	PROCEEDINGS OF SPIE Vol. 4688 (2002), Emerging Lithographic Technologies IV, "Lossless Compression Techniques for Maskless Lithography Data," Vito DAI et al.

EXAMINER

Joseph R. Rhyne

DATE CONSIDERED

9/15/03

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